UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

| APPLICATION NO. | FILING DATE | FIRST NAMED INVENTOR | ATTORNEY DOCKET NO. | CONFIRMATION NO. |
|-------------------------------|------------------------------------|-------------------------|---------------------|------------------|
| 10/536,483 05/24/2005 | | Bruce B Doris | FIS920020105 | 6798 |
| | 7590 05/16/200 NAL BUSINESS MAC | 8 CHINES CORPORATION | EXAM | INER |
| DEPT. 18G | | | LIU, BEN | JAMIN T |
| BLDG. 300-482 2070 ROUTE 5 | | ART UNIT | PAPER NUMBER | |
| HOPEWELL JU | UNCTION, NY 12533 | | 2826 | |
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| | | | MAIL DATE | DELIVERY MODE |
| | | | 05/16/2008 | PAPER |

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

| | Application No. Applicant(s) | | | | | |
|--|--|--------------|--|--|--|--|
| Interview Summary | 10/536,483 | DORIS ET AL. | | | | |
| interview Summary | Examiner | Art Unit | | | | |
| | Benjamin Tzu-Hung Liu | 2826 | | | | |
| All participants (applicant, applicant's representative, PTO | personnel): | | | | | |
| (1) <u>Benjamin Tzu-Hung Liu</u> . | (3) | | | | | |
| (2) <u>Joseph P. Abate</u> . | (4) | | | | | |
| Date of Interview: <u>12 May 2008</u> . | | | | | | |
| Type: a)⊠ Telephonic b)□ Video Conference c)□ Personal [copy given to: 1)□ applicant | 2) <mark> applicant's representative</mark> | e] | | | | |
| Exhibit shown or demonstration conducted: d)☐ Yes If Yes, brief description: | | | | | | |
| Claim(s) discussed: <u>none</u> . | | | | | | |
| Identification of prior art discussed: none. | | | | | | |
| Agreement with respect to the claims f) was reached. g) was not reached. h) \square N/A. | | | | | | |
| Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: <u>Attorney called and pointed out a mistake made on the examiner's amendment submitted 5/1/2008</u> , in claim 1 line 8, after "the PMOS and NMOS devices are FinFET devices, and further wherein an etch" and before "layer is disposed under the compressive layer and tensile layer", replace "step" withstop | | | | | | |
| (A fuller description, if necessary, and a copy of the amend allowable, if available, must be attached. Also, where no dallowable is available, a summary thereof must be attached. | copy of the amendments that w | | | | | |
| THE FORMAL WRITTEN REPLY TO THE LAST OFFICE ACTION MUST INCLUDE THE SUBSTANCE OF THE INTERVIEW. (See MPEP Section 713.04). If a reply to the last Office action has already been filed, APPLICANT IS GIVEN A NON-EXTENDABLE PERIOD OF THE LONGER OF ONE MONTH OR THIRTY DAYS FROM THIS INTERVIEW DATE, OR THE MAILING DATE OF THIS INTERVIEW SUMMARY FORM, WHICHEVER IS LATER, TO FILE A STATEMENT OF THE SUBSTANCE OF THE INTERVIEW. See Summary of Record of Interview requirements on reverse side or on attached sheet. | | | | | | |
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| Francisco Notas Varianda de la forma de la composito de la com | /Minh-Loan T. Tran/ Primary Examiner Art Unit 2826 | | | | | |
| Examiner Note: You must sign this form unless it is an | Examiner's signature, if requi | rea | | | | |

Supplemental Notice of Allowability

| Application No. | Applicant(s) | |
|-----------------------|--------------|--|
| 10/536,483 | DORIS ET AL. | |
| Examiner | Art Unit | |
| Beniamin Tzu-Hung Liu | 2826 | |

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|--|--|--|---------------------------|
| | Benjamin Tzu-Hung Liu | 2826 | |
| The MAILING DATE of this communication appearance All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RION of the Office or upon petition by the applicant. See 37 CFR 1.313 | (OR REMAINS) CLOSED in this app or other appropriate communication GHTS. This application is subject to and MPEP 1308. | olication. If not include will be mailed in due | ed course. THIS |
| 1. This communication is responsive to Phone interview made | <u>e on 5/12/08</u> . | | |
| 2. ☑ The allowed claim(s) is/are <u>1-8</u> . | | | |
| 3. | e been received. been received in Application No cuments have been received in this is of this communication to file a reply of this application. itted. Note the attached EXAMINER as reason(s) why the oath or declarate to be submitted. Son's Patent Drawing Review (PTO- as Amendment / Comment or in the Comment or in the Comment of BIOLOGICAL MATERIAL in sit of BIOLOGICAL MATERIAL in | national stage applicant complying with the recomplying attached of the state | quirements OTICE OF |
| Attachment(s) 1. ☐ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☐ Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material | 5. ☐ Notice of Informal P 6. ☐ Interview Summary Paper No./Mail Dat 7. ☑ Examiner's Amendn 8. ☐ Examiner's Stateme 9. ☐ Other /Minh-Loan T. Tran/ Primary Examiner Art Unit 2826 | (PTO-413), e nent/Comment | wance |

SUPPLEMENTAL EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Joseph P. Abate on 5/12/08.

Regarding examiners amendment submitted 5/1/2008, in claim 1 line 8, after "the PMOS and NMOS devices are FinFET devices, and further wherein an etch" and before "layer is disposed under the compressive layer and tensile layer", replace "step" with -- stop--.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Benjamin Tzu-Hung Liu whose telephone number is (571)272-6009. The examiner can normally be reached on Mon-Fri 9:30 AM-6:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Sue A. Purvis can be reached on 571 272 1236. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Application/Control Number: 10/536,483 Page 3

Art Unit: 2826

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

BTL 5/12/08

/Minh-Loan T. Tran/ Primary Examiner Art Unit 2826

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

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Supplemental Notice of Allowability

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| Examiner | Art Unit | |
| Benjamin Tzu-Hung Liu | 2826 | |

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|---|--|--|---------------------------|
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| 1. This communication is responsive to <u>IDS filed on 4/15/08</u> . | | | |
| 2. ☑ The allowed claim(s) is/are <u>1-8</u> . | | | |
| 3. | e been received. be been received in Application No cuments have been received in this is of this communication to file a reply of this application. itted. Note the attached EXAMINER' ces reason(s) why the oath or declarates be submitted. son's Patent Drawing Review (PTO- ces Amendment / Comment or in the Ces cast of BIOLOGICAL MATERIAL in | national stage applicational stage application of the front (not the d). | quirements NOTICE OF |
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| | Primary Examiner Art Unit 2826 | | |

| Interview Summary 10/536,483 DORIS ET AL. Examiner Art Unit Benjamin Tzu-Hung Liu 2826 All participants (applicant, applicant's representative, PTO personnel): (1) Benjamin Tzu-Hung Liu (examiner). (3) (2) Joseph P. Abate (Attorney). (4) Date of Interview: 29 April 2008. Type: a) Telephonic b) Video Conference c) Personal [copy given to: 1) applicant 2) applicant's representative] Exhibit shown or demonstration conducted: d) Yes f Yes, brief description: Claim(s) discussed: 1. Identification of prior art discussed: 2007/0023843. Agreement with respect to the claims f) was reached. g) was not reached. h) N/A. Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: Agreement was reached that in claim 1, line 8, after "the PMOS and NMOS devices are FinFET devices" delete ".", and insert, and further wherein an etch step layer is disposed under the | | | | | |
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| compressive layer and tensile layer | | | | | |
| (A fuller description, if necessary, and a copy of the amendments which the examiner agreed would render the claims allowable, if available, must be attached. Also, where no copy of the amendments that would render the claims allowable is available, a summary thereof must be attached.) | | | | | |
| THE FORMAL WRITTEN REPLY TO THE LAST OFFICE ACTION MUST INCLUDE THE SUBSTANCE OF THE INTERVIEW. (See MPEP Section 713.04). If a reply to the last Office action has already been filed, APPLICANT IS GIVEN A NON-EXTENDABLE PERIOD OF THE LONGER OF ONE MONTH OR THIRTY DAYS FROM THIS INTERVIEW DATE, OR THE MAILING DATE OF THIS INTERVIEW SUMMARY FORM, WHICHEVER IS LATER, TO FILE A STATEMENT OF THE SUBSTANCE OF THE INTERVIEW. See Summary of Record of Interview requirements on reverse side or on attached sheet. | | | | | |
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| /Minh-Loan T. Tran/ Primary Examiner | | | | | |
| Examiner Note: You must sign this form unless it is an Attachment to a signed Office action Attachment to a signed Office action | | | | | |
| Attachment to a signed Office action. U.S. Patent and Trademark Office PTOL-413 (Rev. 04-03) Interview Summary Paper No. 20080429 | | | | | |

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Joseph P. Abate on 4/29/2008.

The application has been amended as follows:

In claim 1 line 8, after "the PMOS and NMOS devices are FinFET devices" delete ".", and insert --, and further wherein an etch step layer is disposed under the compressive layer and tensile layer.—

The following is an examiner's statement of reasons for allowance:

Prior art does not discloses a semiconductor device particularly characterizing the limitation, wherein an etch step layer is disposed under the compressive layer and tensile layer as recited in claim 1.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Application/Control Number: 10/536,483 Page 3

Art Unit: 2826

BTL

04/2008 /Minh-Loan T. Tran/

Primary Examiner

Art Unit 2826



UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

BIB DATA SHEET

CONFIRMATION NO. 6798

| SERIAL NUM | BER | FILING or | | | CLASS | GRO | OUP ART | UNIT | ATTORNEY DOCKET | |
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| ADDRESS INTERNATIONAL BUSINESS MACHINES CORPORATION DEPT. 18G BLDG. 300-482 2070 ROUTE 52 HOPEWELL JUNCTION, NY 12533 UNITED STATES | | | | | | | | | | |
| TITLE | | | | | | | | | | |
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Doc code :IDS Doc description: Information Disclosure Statement (IDS) Filed

PTO/SB/08a (03-08)
Approved for use through 04/30/2008. OMB 0651-0031
Ormation Disclosure Statement (IDS) Filed
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

| | Application Number 10536483 | | 10536483 | |
|--|-----------------------------|---|-----------------|--|
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Not for submission under 37 CFR 1.99) | Filing Date | | 2005-05-24 | |
| | First Named Inventor | First Named Inventor Bruce B. Doris, et al. | | |
| | Art Unit | | 2826 | |
| | Examiner Name | Benja | min T. Liu | |
| | Attorney Docket Number | | FIS920020105US1 | |

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Not for submission under 37 CFR 1.99)

| Application Number | | 10536483 | | |
|----------------------------|-------|------------------|--|--|
| Filing Date | | 2005-05-24 | | |
| First Named Inventor Bruce | | B. Doris, et al. | | |
| Art Unit | | 2826 | | |
| Examiner Name | Benja | min T. Liu | | |
| Attorney Docket Number | | FIS920020105US1 | | |

| Examiner Initials* | Cite No | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc), date, pages(s), volume-issue number(s), publisher, city and/or country where published. | | | | | | | | | |
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| If you wish to add additional non-patent literature document citation information please click the Add button Add | | | | | | | | | | | |
| EXAMINER SIGNATURE | | | | | | | | | | | |
| Examiner Signa | | iture | /Benjamin Tzu-Hung Liu/ | Date Considered | 04/29/2008 | | | | | | |
| *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through a citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | | | | | | |
| ¹ See Kind Codes of USPTO Patent Documents at <u>www.USPTO.GOV</u> or MPEP 901.04. ² Enter office that issued the document, by the two-letter code (WIPO Standard ST.3). ³ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁴ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁵ Applicant is to place a check mark here if English language translation is attached. | | | | | | | | | | | |

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Not for submission under 37 CFR 1.99)

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| Art Unit | | 2826 |
| Examiner Name | Benja | min T. Liu |
| Attorney Docket Number | | FIS920020105US1 |

| | CERTIFICATION STATEMENT | | | | | | | | | |
|------------|---|-------------------|---------------------|------------|--|--|--|--|--|--|
| Plea | Please see 37 CFR 1.97 and 1.98 to make the appropriate selection(s): | | | | | | | | | |
| × | That each item of information contained in the information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement. See 37 CFR 1.97(e)(1). | | | | | | | | | |
| OR | OR | | | | | | | | | |
| | That no item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the person signing the certification after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of the information disclosure statement. See 37 CFR 1.97(e)(2). | | | | | | | | | |
| | See attached certification statement. | | | | | | | | | |
| | Fee set forth in 37 CFR 1.17 (p) has been submitted herewith. | | | | | | | | | |
| | | | | | | | | | | |
| | SIGNATURE A signature of the applicant or representative is required in accordance with CFR 1.33, 10.18. Please see CFR 1.4(d) for the form of the signature. | | | | | | | | | |
| Signature | | /Joseph P. Abate/ | Date (YYYY-MM-DD) | 2008-04-15 | | | | | | |
| Name/Print | | Joseph P. Abate | Registration Number | 30238 | | | | | | |
| | | | | | | | | | | |

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1 hour to complete, including gathering, preparing and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. **SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.**

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- 7. A record from this system of records may be disclosed, as a routine use, to the Administrator, General Services, or his/her designee, during an inspection of records conducted by GSA as part of that agency's responsibility to recommend improvements in records management practices and programs, under authority of 44 U.S.C. 2904 and 2906. Such disclosure shall be made in accordance with the GSA regulations governing inspection of records for this purpose, and any other relevant (i.e., GSA or Commerce) directive. Such disclosure shall not be used to make determinations about individuals.
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